

NOVEL TECHNIQUES FOR MEMS-BASED VOC SENSORS USING NANOSTRUCTURED METAL OXIDES

by

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DEDICATED

TO

MY BROTHER

NISHANT

Certificate

This is to certify that the thesis entitled, “**Novel Techniques for MEMS-Based VOC Sensors Using Nanostructured Metal Oxides**”, being submitted by **Mr. Hardik Jeetendra Pandya** for the award of the degree of **Doctor of Philosophy (Ph.D.)** to the Indian Institute of Technology Delhi, New Delhi, is a record of bonafide research work carried out by him under our guidance and supervision.

In our opinion, the thesis has reached the standard of fulfilling the requirements of all the regulations related to the degree. The results contained in this thesis have not been submitted in part or full, to any other University or Institute for the award of any degree or diploma.

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ABSTRACT

In the present dissertation, an attempt has been made to develop a few novel techniques for fabricating low-cost sensors for detecting vapours of volatile organic compound (VOC) using Micro-Electro-Mechanical-Systems (MEMS) technologies. For this purpose, different metal oxides have been investigated as sensing material. One of the objectives of the present work is to develop sensors, which are capable of detecting VOCs at nearby room temperatures (30°C - 100°C). This has been accomplished by using nanostructured metal oxides rather than the thin films of these materials.

The metal oxides used in present study are: indium tin oxide (ITO), zinc oxide (ZnO) and copper oxide (CuO). The ITO films are prepared by RF magnetron sputtering using a 3-inch diameter ITO target in argon atmosphere in the pressure range 5-20 mTorr at RF power of 100-300 W. The target-to-substrate spacing is fixed at 50 mm. Films having thickness in range of 0.1-0.3 μm are investigated. The effect of deposition parameters (RF power and sputtering pressure) on various properties such as deposition rate, crystallinity and surface morphology are investigated. As these films are to be used for sensing purpose, the crystallinity is an important issue as improved crystallinity of the films enhances the sensitivity of detection. The ITO film prepared at 200W RF power and 10 mTorr sputtering pressure and annealed at 450 °C for 1 h show a nano-crystalline phase having fairly uniform grain size. Accordingly, we have used these parameters for preparing nano-crystalline ITO film. The ITO film is deposited and patterned using lift-off technique on the MEMS platform having an integrated heater. A low cost material (Ni) is used for microheater fabrication while aluminum is used for inter digital electrode (IDE) to measure the resistance of the

sensing layer. The lift-off technique is used for patterning the ITO as its etchant affects the Al IDE (and vice-a-versa). The complete process of fabricating MEMS based sensor having integrated microheater and using ITO as sensing film is presented. A set up was especially established to test the sensors for different concentrations of VOCs. The sensors are tested for different VOCs (methanol, acetone, ethanol and IPA).

The nanostructured ZnO was prepared in a novel manner. Zn film is deposited on oxidized silicon substrate using thermal evaporation technique. The Zn films are annealed at different temperatures in air for different durations. It is demonstrated that Zn film is converted into nanostructured ZnO on annealing in air. It has been further demonstrated that the use of nanostructured ZnO results in considerable reduction in the operating temperature of the sensor. The power consumption to achieve the desired operating temperature is also significantly reduced by making the sensor on a thin diaphragm obtained by MEMS technologies. The nanostructured ZnO films are integrated with the MEMS processing steps to form a complete sensor. The sensors are tested for different VOCs. It is observed that the sensors fabricated using nanostructured ZnO are capable of detecting VOCs at operating temperatures as low as 100 °C.

An innovative technique for fabricating sensors on planar thermally isolated MEMS platform is presented. The sensors fabricated using this technique have high mechanical strength and also consume low power.

Copper oxide is the third (and last) material investigated as sensing layer in the present work. A new and simple technique for preparing long and uniformly aligned copper oxide (CuO) nanowires, by annealing the copper (Cu) film deposited on oxidized silicon, is presented. The Cu films are deposited using RF magnetron

sputtering technique. The annealing time and temperature are optimized. The sensor is fabricated using CuO nanowires using a simple 2-mask process. The Cr–Au film is used as inter digital electrode in this case. The copper film of about 3 μm thickness is prepared by RF sputtering process. Thereafter, the wafer is subjected to annealing process at 700 $^{\circ}\text{C}$ in air for 6 h, which converted the Cu film into CuO nanowires. The sensors are tested for different VOCs. It is observed that the sensor is capable of detecting VOC even below 50 $^{\circ}\text{C}$ operating temperature. These sensors have higher sensitivity and faster response time compared to sensors fabricated using other metal oxide materials (ITO and ZnO).

An electronic module for displaying concentration of VOCs is designed and developed. The module is equipped with signal conditioning unit, microcontroller and liquid crystal display device. Thus, a completed sensor system with electronics is designed and developed in the present work.

The thesis concludes by suggesting the scope of further research in this area.

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